

ABSTRACT OF THE DISCLOSURE

It is an object of the present invention to provide a substrate inspection system, a substrate inspection method, and a substrate inspection apparatus for realizing efficient operation of inspecting both a large region and a small region of a substrate. The present
5 invention includes a first inspection apparatus 11 executing a macro inspection of each of a plurality of substrates 14(1) to 14(n) and outputting information on presence/absence of a defect on each of the substrates; a storage unit 12 storing therein the information on presence/absence of a defect outputted from the first inspection apparatus for each of the substrates; and a second inspection apparatus 13 executing an inspection of a predetermined
10 portion of the substrate. The second inspection apparatus refers to the presence/absence information stored in the storage unit, and inspects a substrate, the one without a defect, of the plural substrates 14(1) to 14(n).